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				Application Number	
				Filing Date	
				First Named Inventor Masami Urano	
				Art Unit	
				Examiner Name	
Sheet	1	of	1	Attorney Docket Number	

U.S. PATENT DOCUMENT					
Examiner Initials*	Cite No. ¹	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number	Kind-Code ² (if known)		
		US			
		US			
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FOREIGN PATENT DOCUMENT							
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Translation ⁶
		Country Code ³	Number ⁴	Kind-Code ⁵ (if known)			
ML		JP	2001-198897	A	07-24-2001	LUCENT TECHNOL INC	ABST
ML		JP	2002-189178	A	07-05-2002	TEXAS INSTR JAPAN LTD	ABST

OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Translation ⁶
ML		Optical Networking: MEMS Mirror Control, ANASOG DEVICES	
ML		Madanagopal et al., Real Time Software Control Of Spring Suspended Micro-Electro-Mechanical (MEM) Devices For Precision Optical Positioning Applications, 2002 International Conference on Optical MEMs 2002, August 2002, pp. 41-42	
ML		Hirao et al., "Circuit Design for High-Speed MEMS Mirror Drive", 2002 IEICE Communications Society Conference, September 11, 2002, pp. 445	
ML		Transistor Technology, the Issue of May 2002, pp. 207 - 212	
ML		"MEMS: Micro Technology, Mega Impact", CIRCUITS & DEVICES, pp. 14-25, March 2001	
ML		Petterson et al., "MOEMS ELECTROSTATIC SCANNING MICROMIRRORS DESIGN AND FABRICATION", Electrochemical Society Proceedings, vol 2002-4, pp. 369- 380	
ML		Sawada et al., "Single Crystalline Mirror Actuated Electrostatically by terraced Electrodes With High-Aspect Ratio Torsion Spring", International Conference on Optical MEMS 2001, September 26, 2001	

Examiner Signature		Date Considered	9/15/05
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